

IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **OZAKI, Takashi, et al.**

Group Art Unit: **2812**

Serial No.: **10/517,765**

Examiner: **Not assigned**

Filed: **February 3, 2006**

P.T.O. Confirmation No.: 6791

**FOR: SUBSTRATE TREATING APPARATUS AND METHOD FOR
MANUFACTURING SEMICONDUCTOR DEVICE**

REQUEST FOR STATUS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Date: September 1, 2006

Sir:


The undersigned attorney requests the status of the above-identified application.

The application was filed on **February 3, 2006**, in the U.S. Patent and Trademark Office
and to date no Office Action has been received.

In the event any fees are required in connection with this paper, please charge Deposit
Account No. 01-2340.

Respectfully submitted,

ARMSTRONG, KRATZ, QUINTOS,
HANSON & BROOKS, LLP


William L. Brooks

Attorney for Applicants
Reg. No. 34,129

WLB/jkw
Atty. Docket No. **040509**
Suite 1000
1725 K Street, N.W.
Washington, D.C. 20006
(202) 659-2930



23850

PATENT TRADEMARK OFFICE